

EAST - (unshin.wsp.1) File View Edit Tools Window Help

☐ Drafts
☐ Pending
☒ Active

L1: (3281) (silicon adj oxynitride).clm. or Si\$1N\$10\$1.clm.
L2: (425) 1 and ((group adj3 nitride) or (III adj nitride))
L3: (261) 2 and ((silicon or si) near4 (substrate or wafer))
L4: (21) 3 and (GaN.clm. or (group adj2 nitride).clm. or (III ad
L5: (2) 1 and ((group adj III adj nitride).clm. or (group adj "1
L6: (29) 1 and GaN and (silicon adj oxynitride)
L7: (8) 1 and GaN.clm. and (silicon adj oxynitride)
L8: (2) 6 and (GaN.clm. and (III adj3 nitride).clm. or ("III" ad
L9: (9) 8 and (GaN.clm. or (III adj3 nitride).clm. or ("III" ad

☐ Failed
☒ Saved

(0) ("(thinadjfilm)nearresistor").PN.
(0) ("(thinadjfilm)nearresistor").PN.
(150130) thin adj film
(14857) (thin adj film) and resistor
(2054) ((thin adj film) and resistor) and ((thin adj film) near
(1735) (((thin adj film) and resistor) and ((thin adj film) near
(801) (((thin adj film) and resistor) and ((thin adj film) near
(499) (((thin adj film) and resistor) and ((thin adj film) near

6 and (GaN.clm. or (III adj3 nitride).clm. or ("III" adj3 nitride).clm.)

	U	I	PT	P	Document ID	Issue Dat	Pages	Title	Current OR	Current XR	Retrieval	Inventor	S	C	J	
1	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20040113163	20040617	12	Light emitting device	257/88			Steigerwald, Daniel A. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20040110350	20040610	12	Method of making a nanoscale electronic de	438/299			Pang, Harry F. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20040105473	20040603	16	Semiconductor laser	372/45	372/49		Tojo, Tsuyoshi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
4	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030102490	20030605	49	Semiconductor device and its manufacturing m	257/192	257/E21.06		Kubo, Minoru et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
5	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020182889	20021205	16	FREE STANDING SUBSTRATES BY LASER-IND	438/778	257/E21.11		Solomon, Glenn S. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
6	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020024981	20020228	16	Semiconductor laser	372/45			Tojo, Tsuyoshi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
7	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6773616 B1	20040810	14	Formation of nanoscale wires	216/41	216/66; 216/74;		Chen, Yong et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
8	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6498113 B1	20021224	15	Free standing substrates by laser-ind	438/778	257/E21.11		Solomon, Glenn S. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
9	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 5563428 A	19961008	7	Layered structure of a substrate, a dielectric	257/77	257/103; 257/201;		Ek, Bruce A. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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